IN THE CLAIMS:

1. (Currently Amended) A semiconductor integrated circuit testing method comprising the steps of:

causing a tester to generate a measuring signal to all pins of a semiconductor integrated circuit under test;

generating a trigger signal;

latching said measuring signal by said semiconductor integrated circuit under test and by use of said trigger signal;

storing the latched measuring signal as data into storing means incorporated in said semiconductor circuit under test; and

reading the stored data from said storing means for output to said tester.

2. (Original) The semiconductor integrated circuit testing method according to claim 1, wherein the data stored into said storing means represent electric lengths of all pins of said semiconductor integrated circuit.

3. (Original) The semiconductor integrated circuit testing method according to claim 1, further comprising the steps of creating a calibration data file based on the data sent to said tester.

4. (Currently Amended) The semiconductor integrated circuit testing method according to claim 3, further comprising the step of referencing said calibration data file to

correct waveform timing of said measuring signal upon a functional test performed by said tester.

5. (Original) The semiconductor integrated circuit testing method according to claim 1, wherein said trigger signal is a high-speed clock signal.

6. (Withdrawn)

7. (Currently Amended) A semiconductor integrated circuit testing apparatus for testing signal wiring lengths connecting to all pins of a semiconductor integrated circuit under test, comprising:

a signal generator configured to generate a measuring signal and to transmit the measuring signal to all pins of the semiconductor integrated circuit; and

~~correcting means~~ calibration circuitry for ~~correcting input waveform timing~~ determining waveform timing delay from said wiring lengths based on iterative measurements in time of the measuring signal by said semiconductor integrated circuit under test at each pin.

8. (Currently Amended) The semiconductor integrated circuit testing apparatus according to claim 7, wherein said ~~correcting means~~ calibration circuitry includes:

clock generating means for generating a clock signal;

latching means for latching said measuring signal by use of said clock signal from said clock generating means;

storing means for storing as data said measuring signal latched by said latching means; and

controlling means for retrieving the data held in said storing means for output to an external entity.

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9. (Original) The semiconductor integrated circuit testing apparatus according to claim 8, wherein said latching means, said storing means and said controlling means are incorporated in said semiconductor integrated circuit.

10. (Original) The semiconductor integrated circuit testing apparatus according to claim 8, wherein said latching means is constituted by terminating circuits and latch circuits, and said storing means by FIFO memories and scan FF circuits.

11. (Original) The semiconductor integrated circuit testing apparatus according to claim 8, wherein said clock generating means is a high-speed clock generating circuit for generating a high-speed clock signal.

12. (Withdrawn)

13. (Original) The semiconductor integrated circuit fabricated by use of a semiconductor integrated circuit testing method according to claim 1.

B' Cancel.

14. (Original) The semiconductor integrated circuit fabricated by use of a semiconductor integrated circuit testing apparatus according to claim 7.